

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Jung-Wook Kim, et al. Examiner: Michail Kornakov
Serial No: 10/606,512 Group Art Unit: 1746
Filed: June 26, 2003 Docket: 8054-23 (AW8037US)
For: **METHOD FOR CLEANING A PROCESSING CHAMBER AND METHOD
FOR MANUFACTURING A SEMICONDUCTOR DEVICE**

Mail Stop: Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Office Action dated March 21, 2007, please amend the above-referenced patent application as set forth herein.
